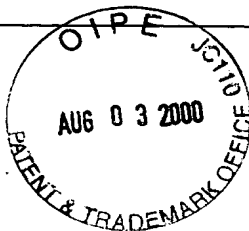


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Li et al.

Application No.: 09/222,588

Filed: December, 28, 1998

Title: PERFORTAED PLASMA CONFINEMENT
RING IN PLASMA REACTORS

Attorney Docket No.: LAM1P098

Examiner: P. Hassanzadeh

Group: 1763

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Assistant Commissioner for Patents, Washington, DC 20231 on July 27, 2000.

Signed: _____

Agnes Spence

AMENDMENT B

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In response to the office action dated May 4, 2000, please enter the following amendments and remarks.

In the ClaimsPlease **CANCEL** claims 16, 18, 20 and 26 as follows:Please **AMEND** claims 1, 17, 24, and 29 as follows:

RECEIVED
AUG - 7 2000
101700 MAIL ROOM

- Sub C1
1. (Twice amended) A plasma processing reactor for processing a substrate comprising:
a chamber;
a top electrode configured to be coupled to a first RF power source having a first RF frequency;
a bottom electrode configured to be coupled to a second RF power source having a second RF frequency that is lower than said first RF frequency;
an insulating shroud that lines an interior of said chamber, said insulating shroud being configured to be electrically floating during said processing; and
- B1

B